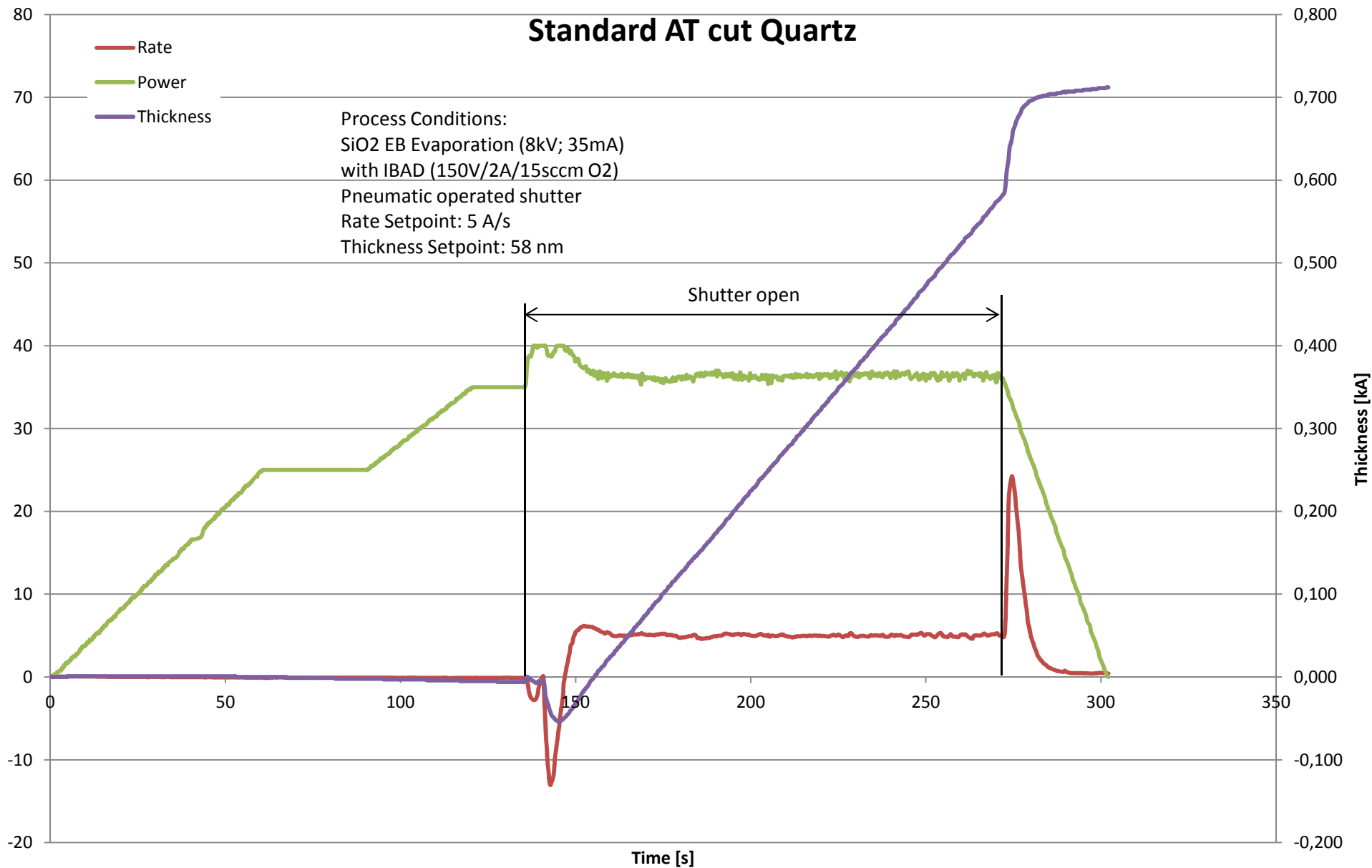


# Standard AT cut Quartz

- Rate
- Power
- Thickness

Process Conditions:  
SiO<sub>2</sub> EB Evaporation (8kV; 35mA)  
with IBAD (150V/2A/15sccm O<sub>2</sub>)  
Pneumatic operated shutter  
Rate Setpoint: 5 A/s  
Thickness Setpoint: 58 nm

Shutter open



# RC cut Quartz

- Rate
- Power
- Thickness

Process Conditions:  
SiO<sub>2</sub> EB Evaporation (8kV; 35mA)  
with IBAD (150V/2A/15sccm O<sub>2</sub>)  
Pneumatic operated shutter  
Rate Setpoint: 5 A/s  
Thickness Setpoint: 58 nm

Shutter open

